



(PRIOR ART)



(PRIOR ART)

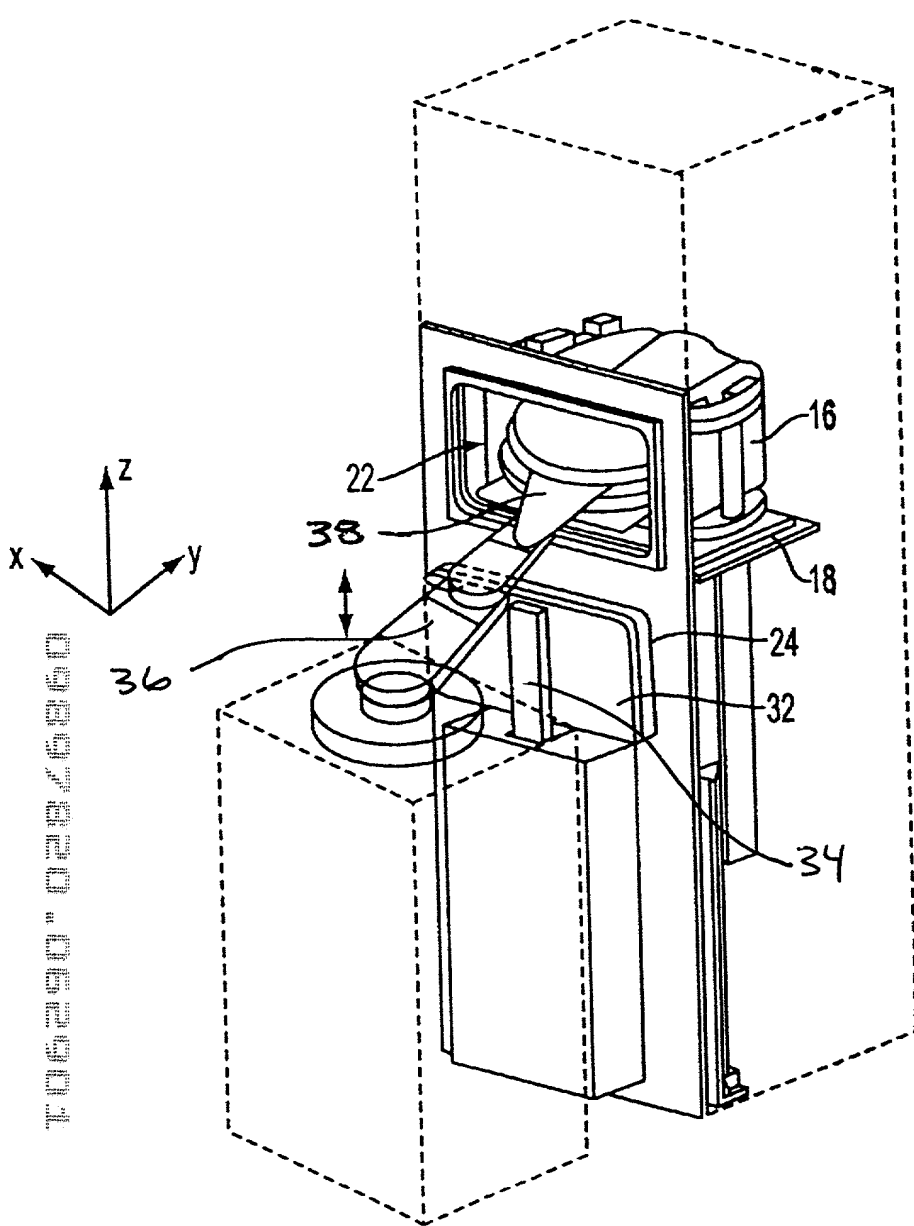


FIG. 1C  
 (PRIOR ART)

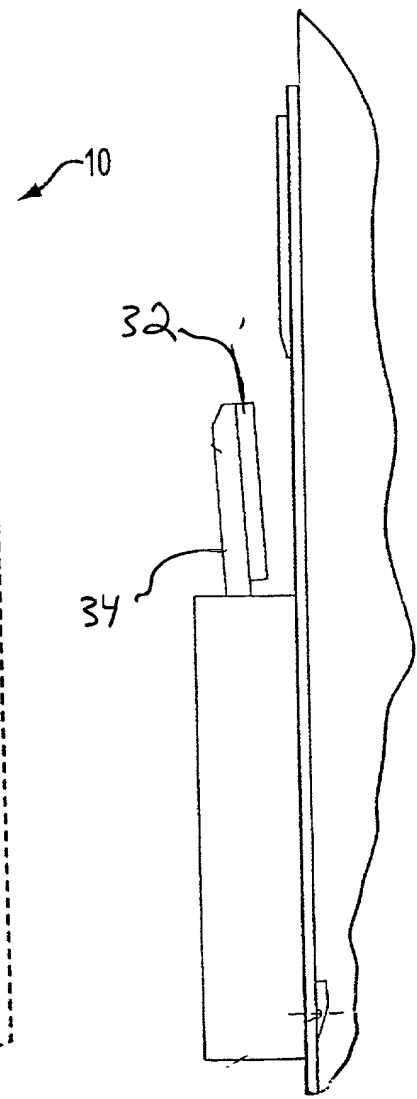
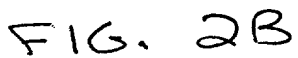
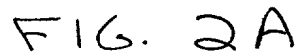
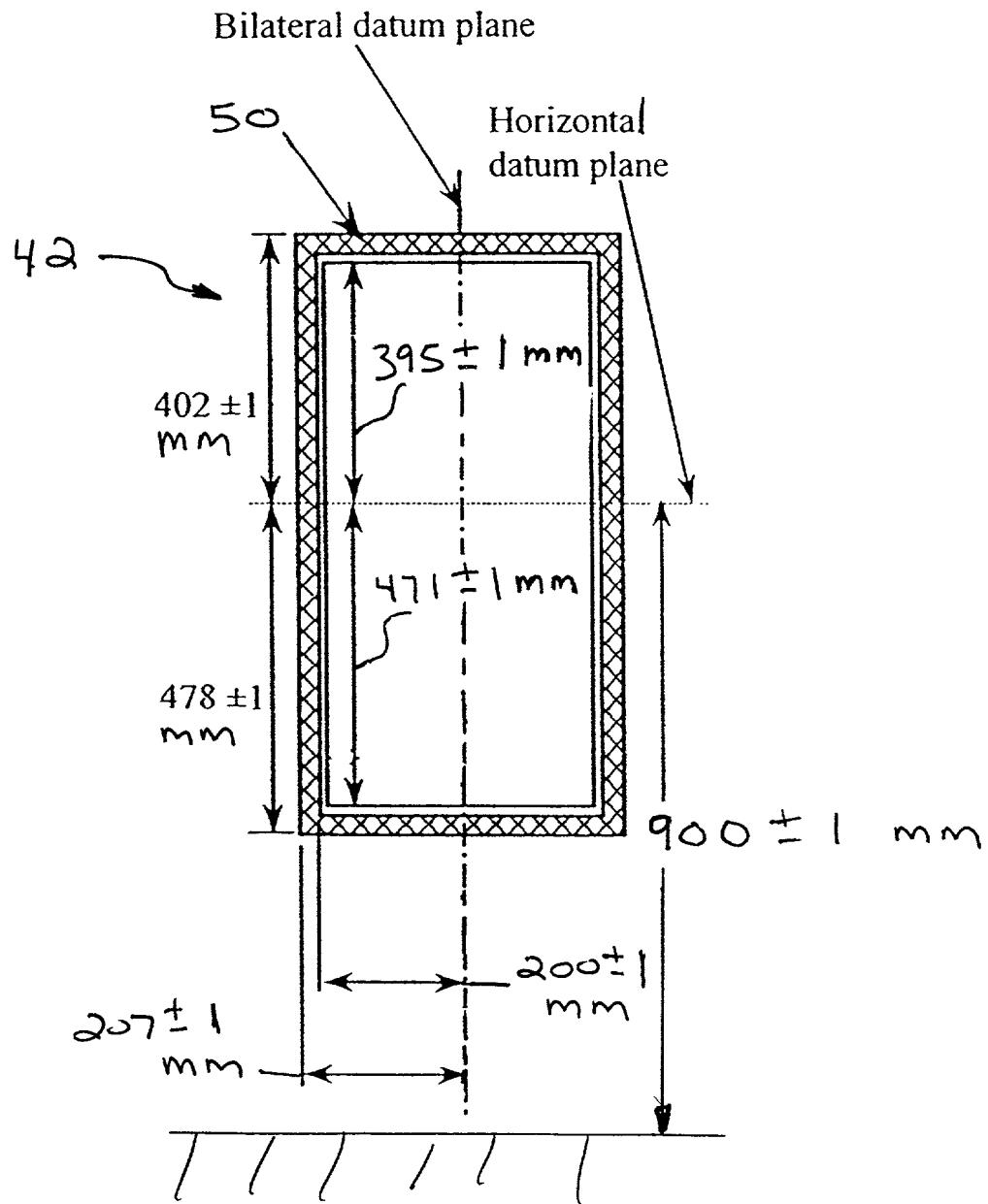


FIG. 1D  
 (PRIOR ART)





FL00K

FIG. 2C

FIG. 2

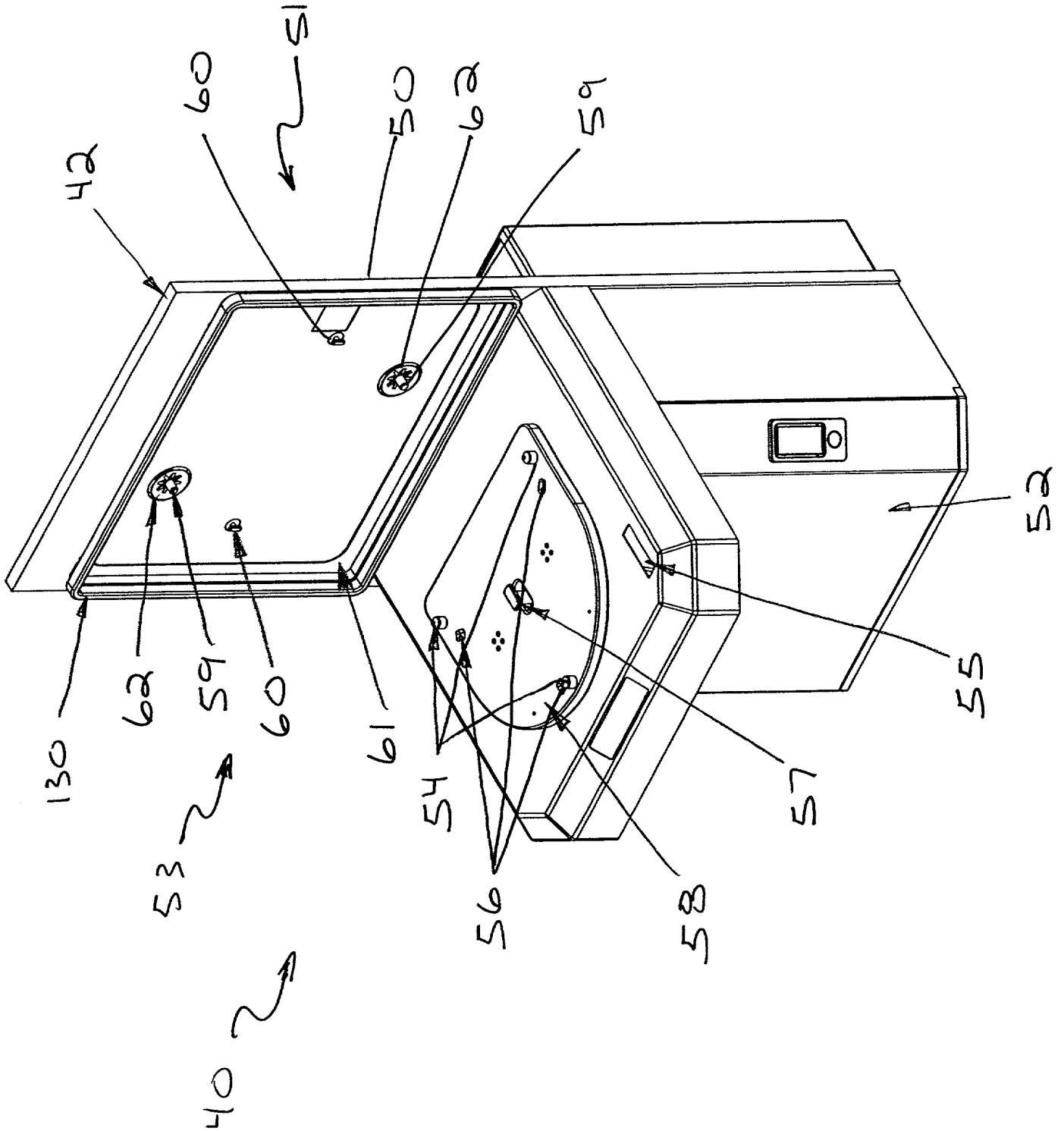


FIG. 3

FIG. 4

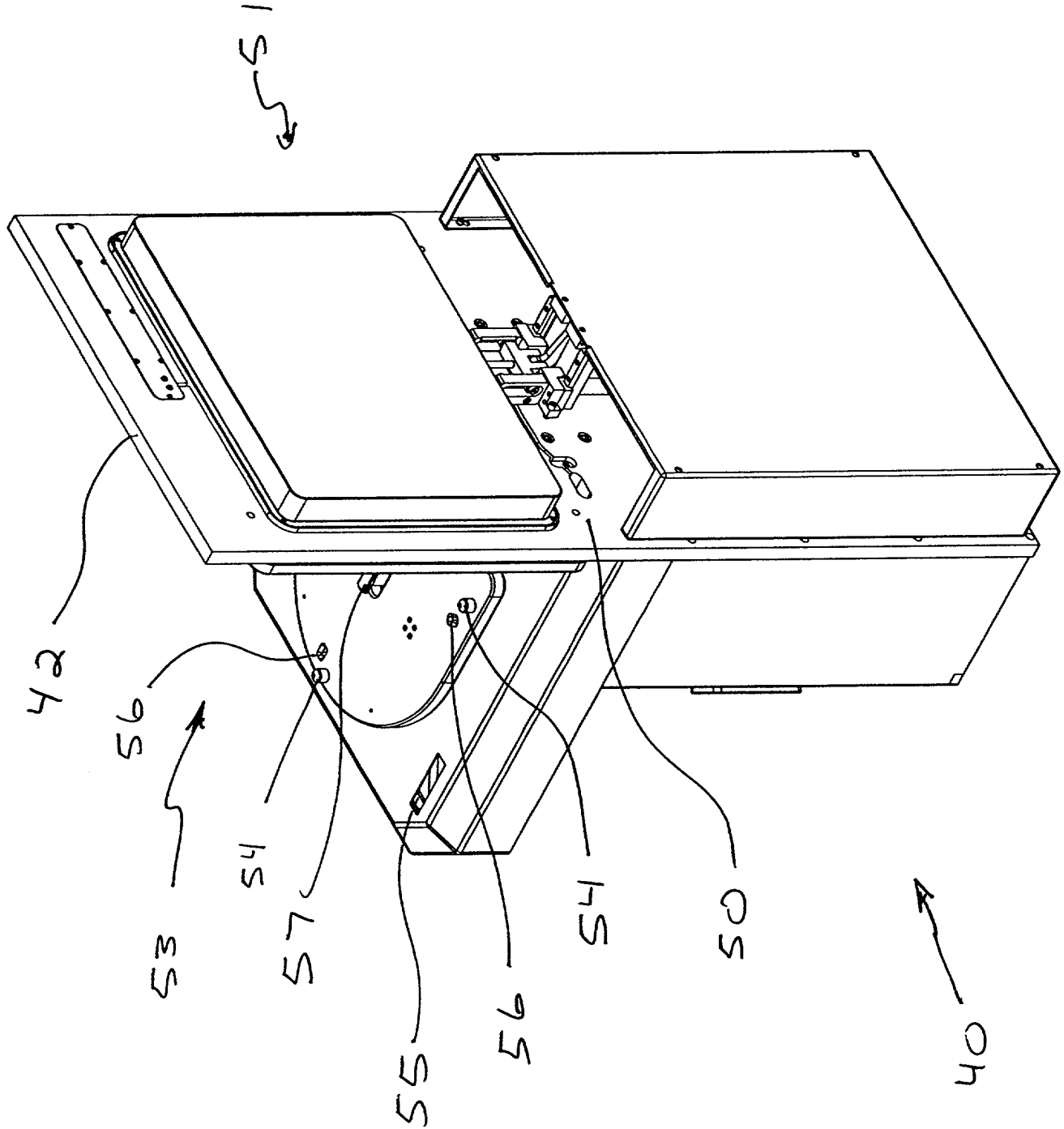
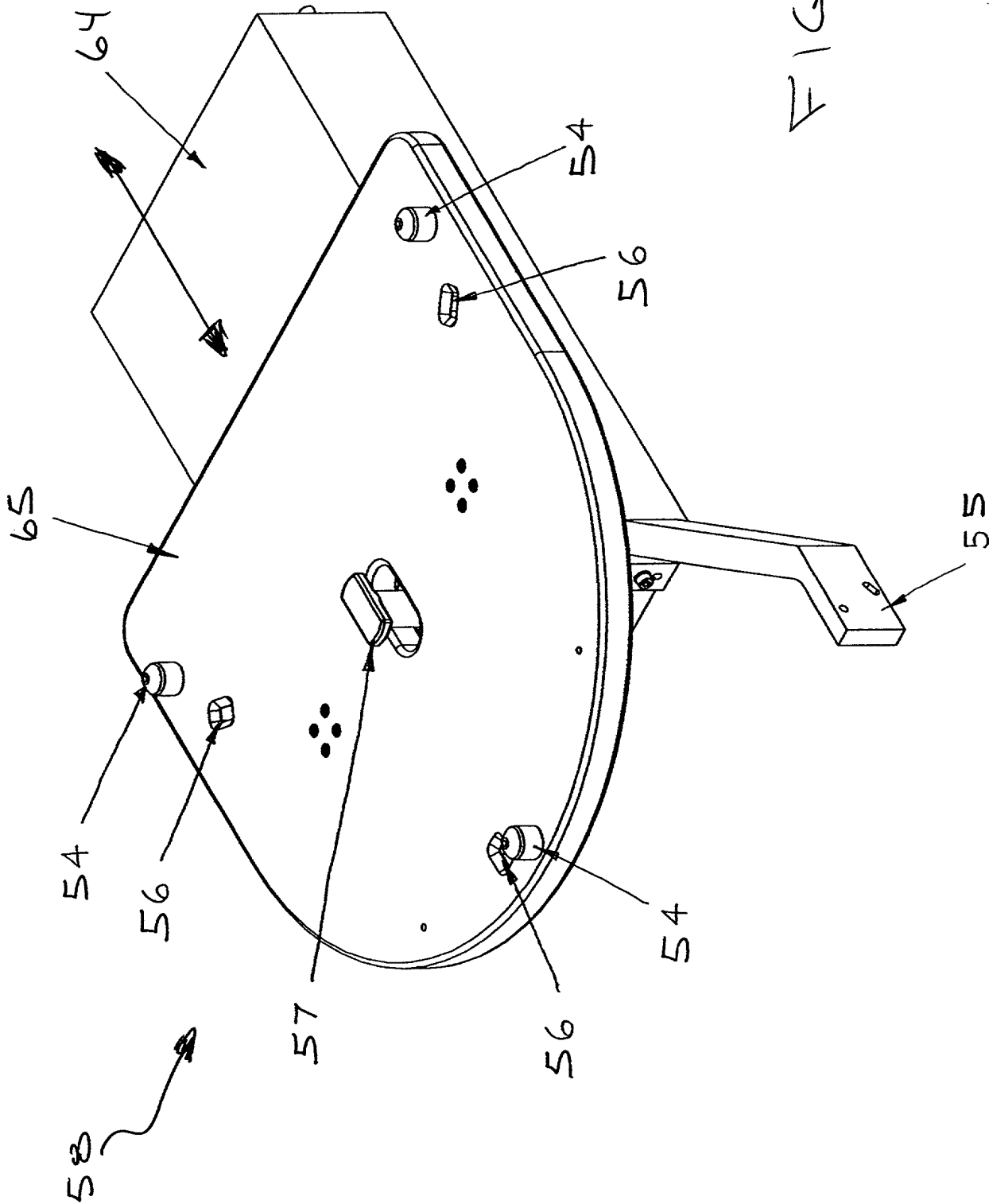


FIG. 4

FIG. 5A



09897820-06290-02826860

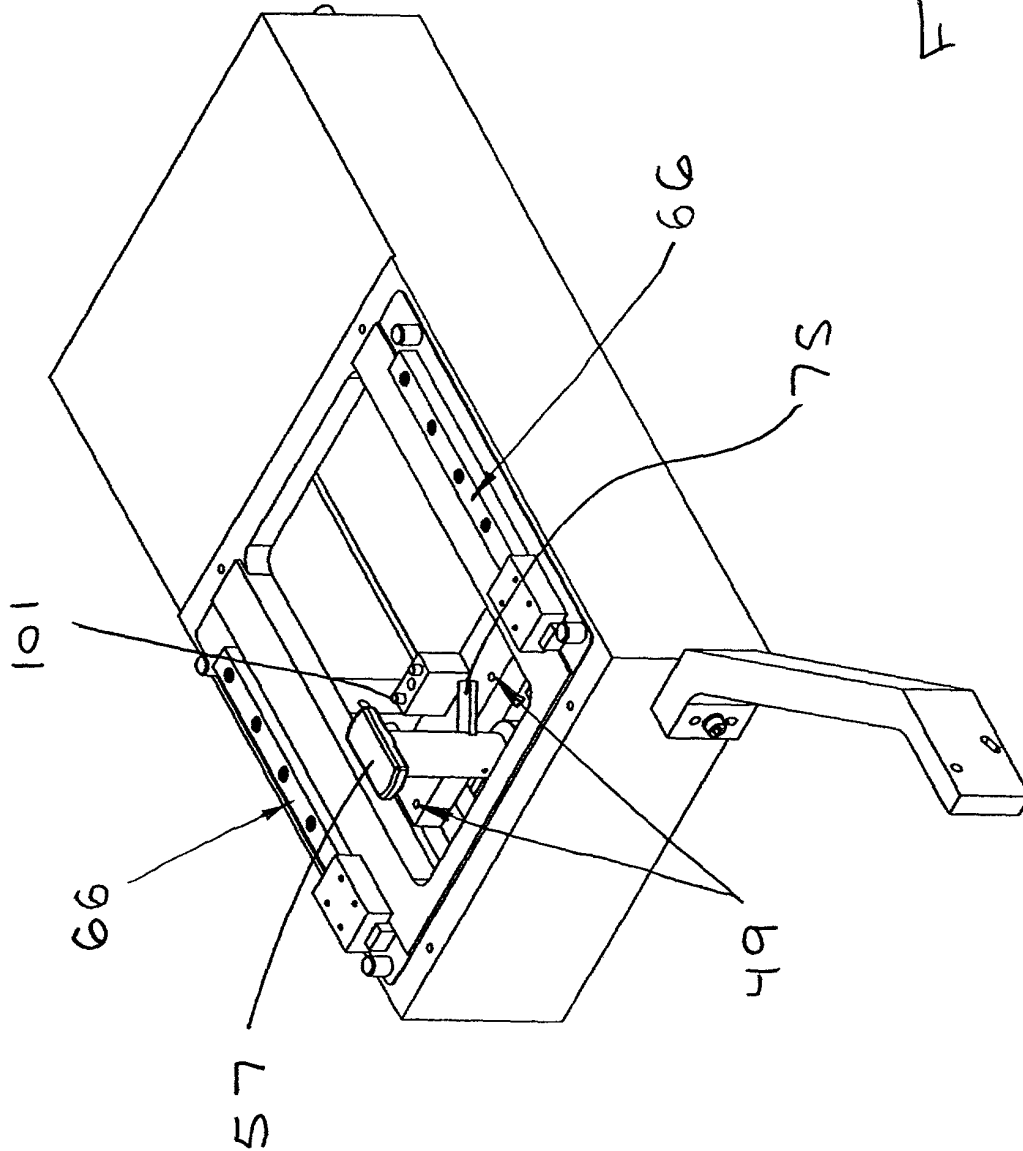
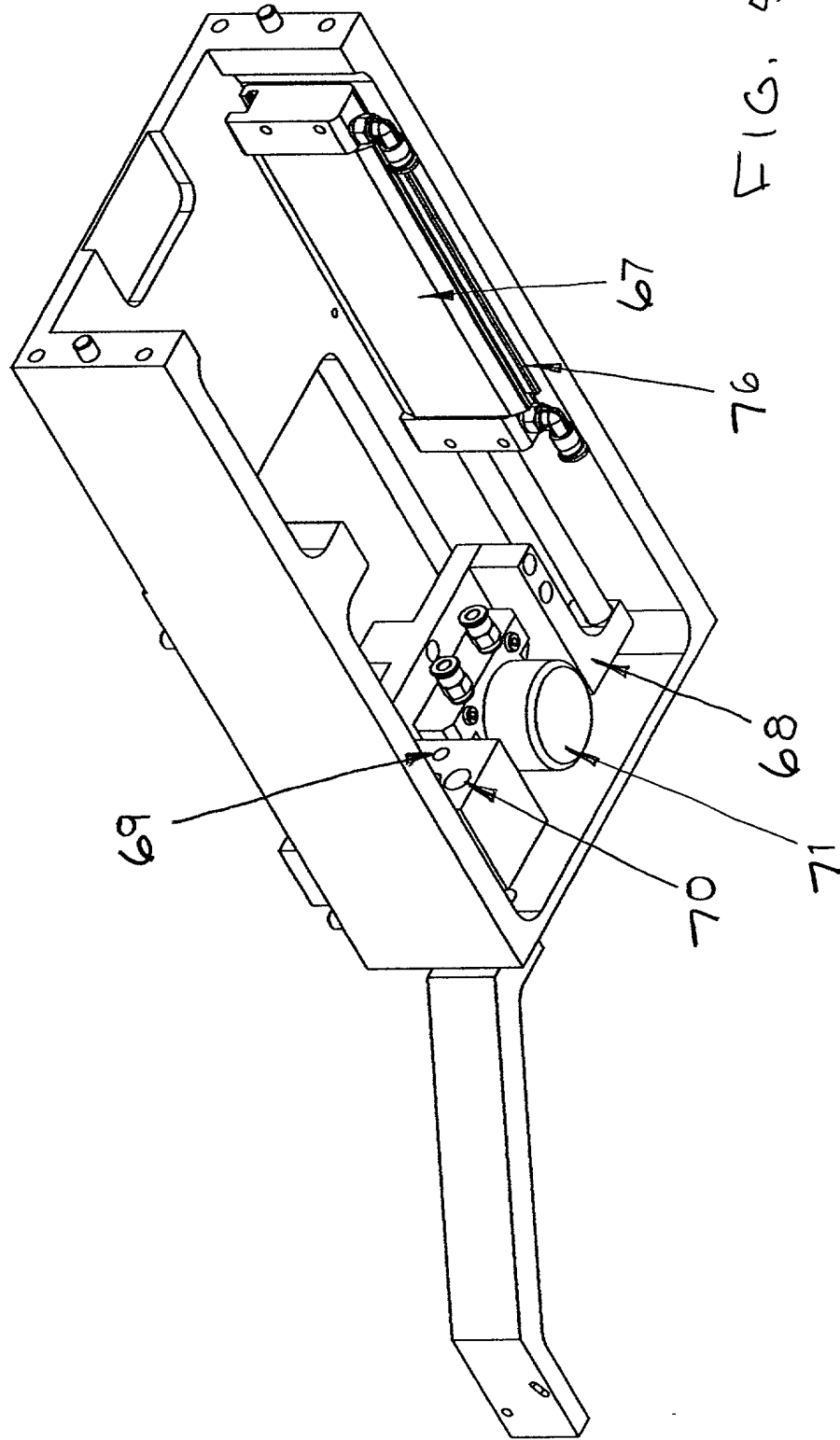


FIG. 5B





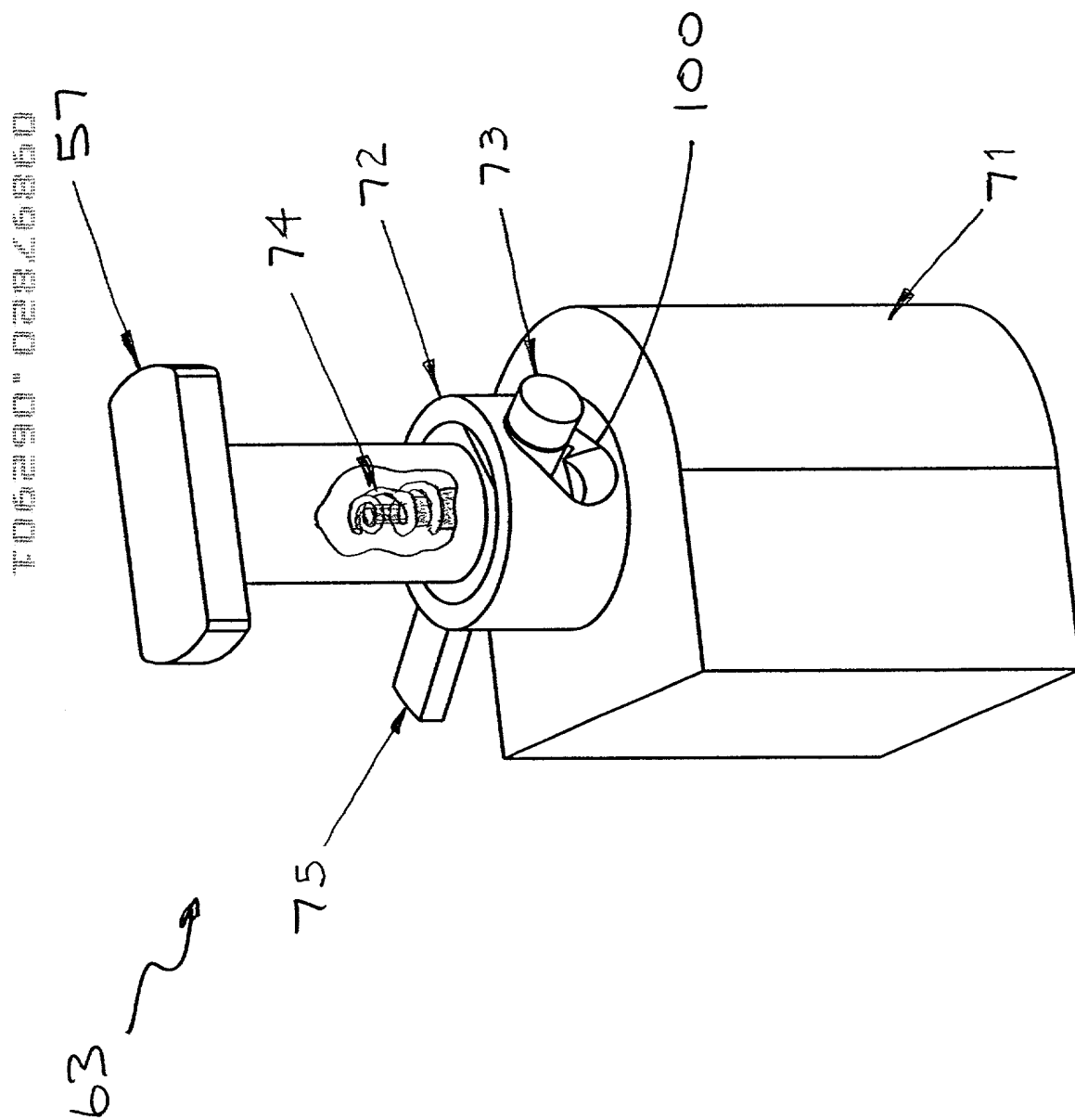


FIG. 5D

09397820-062901

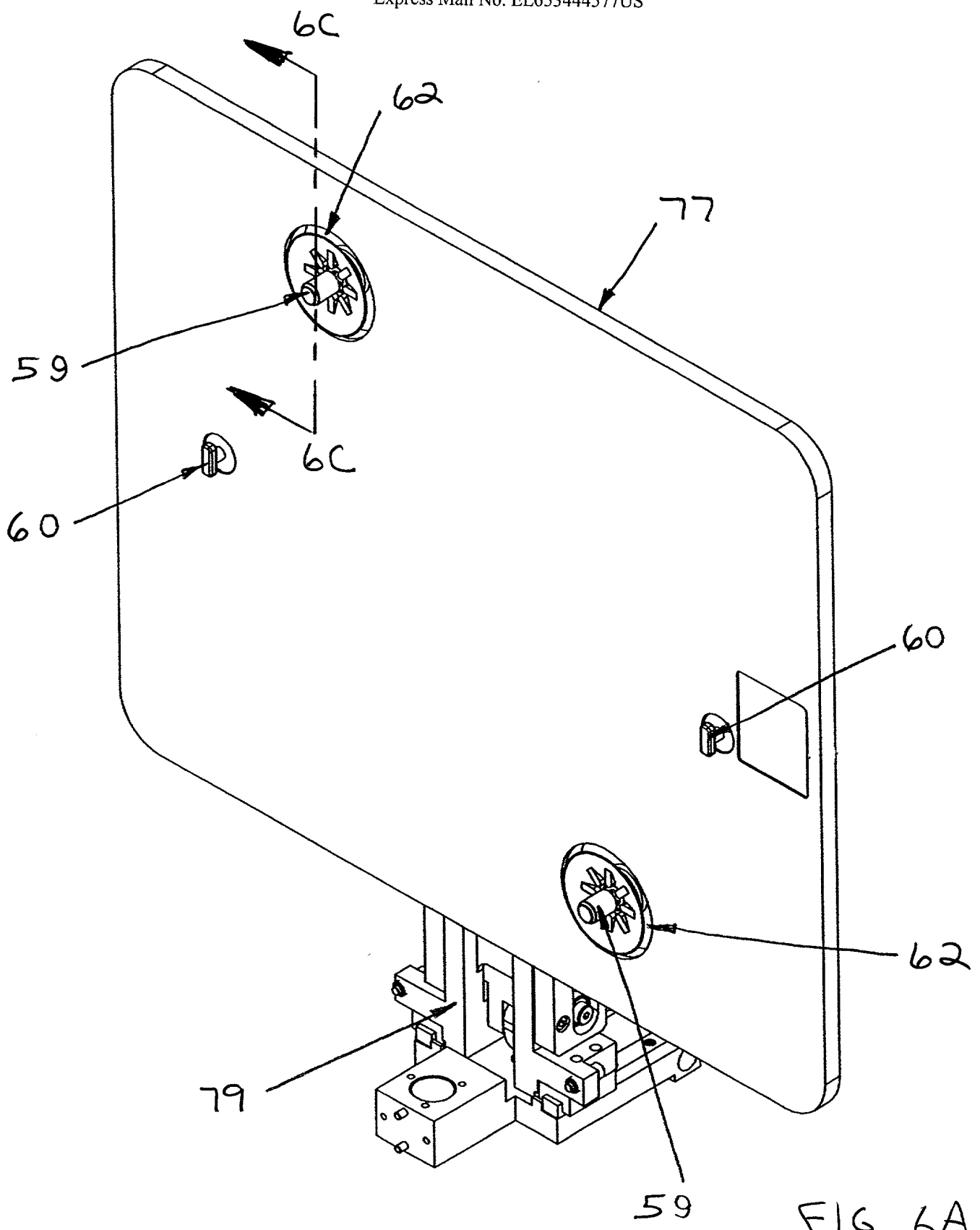
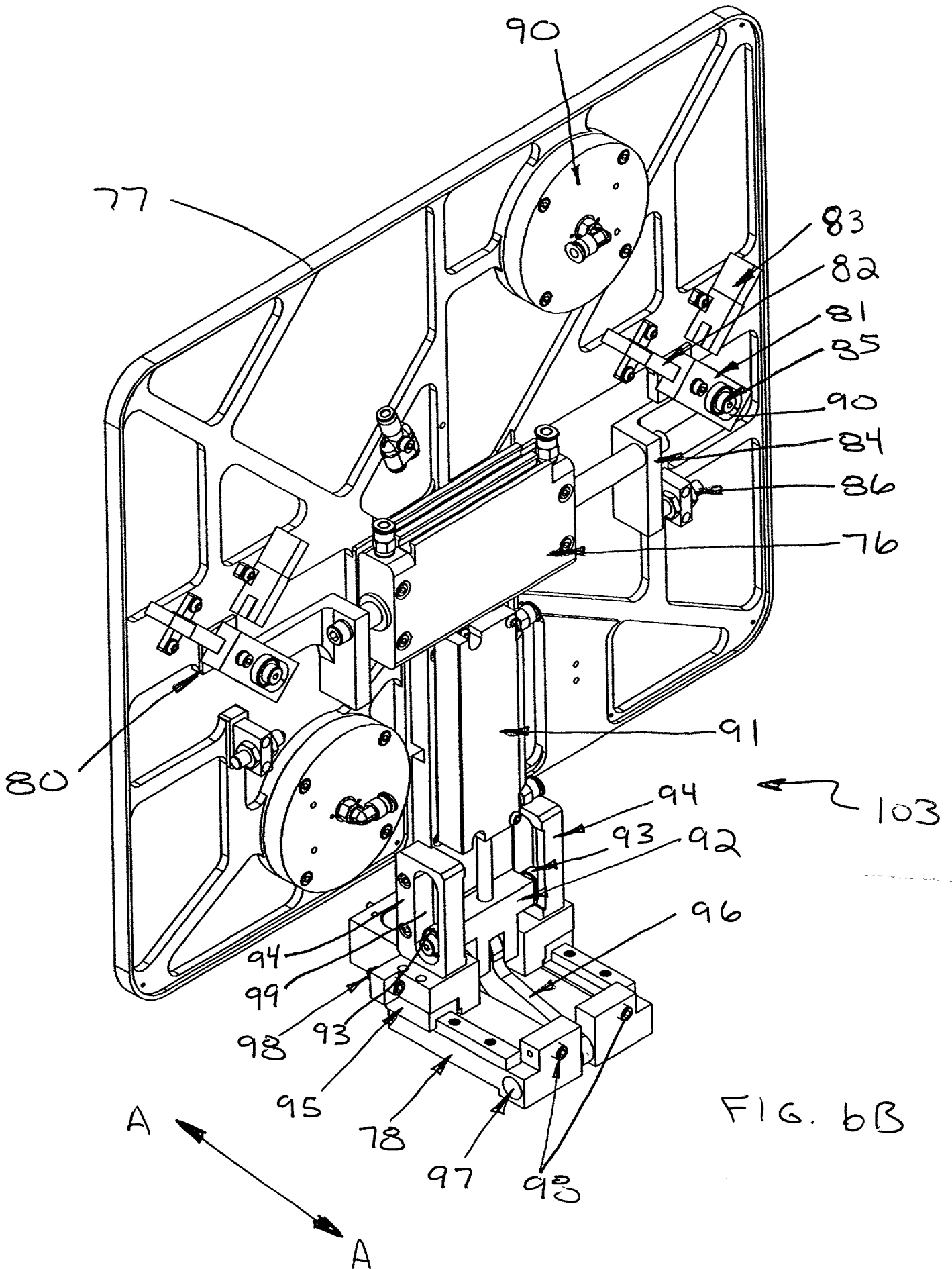


FIG. 6A

FIG. 6B



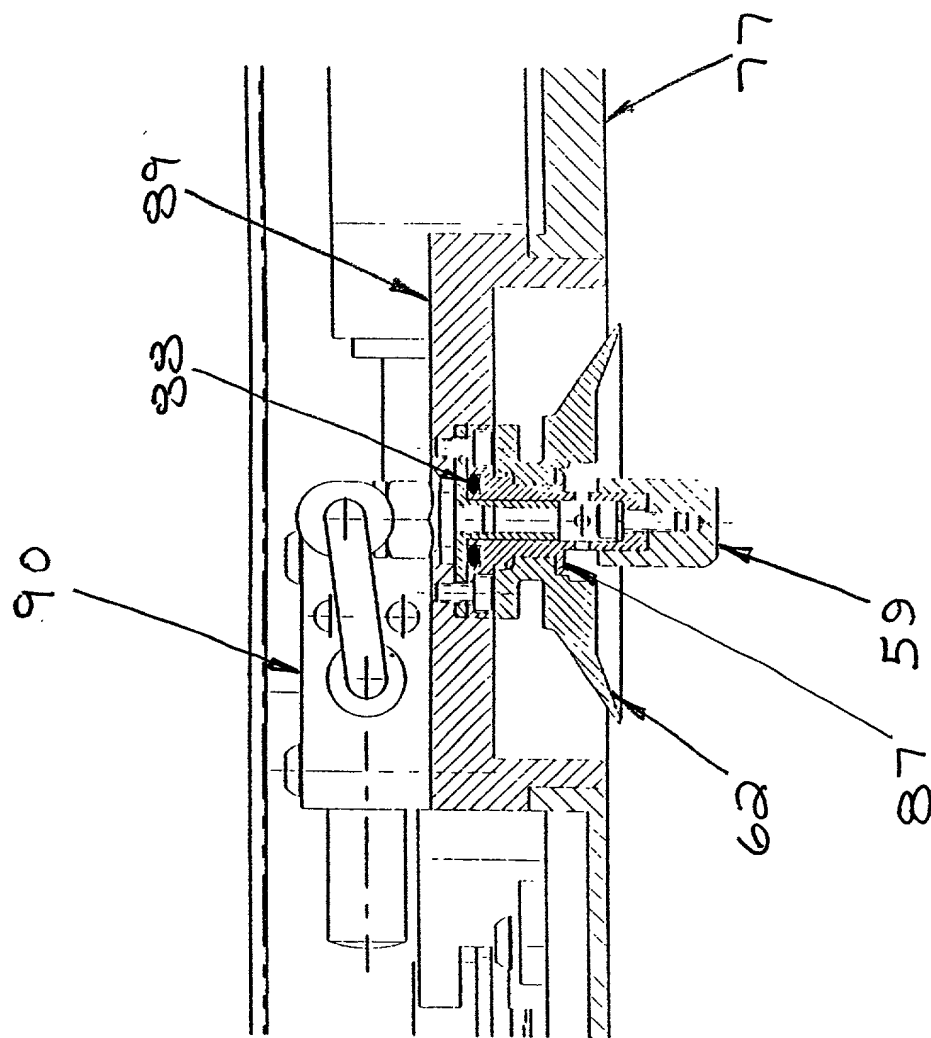


FIG. 6C

106290-02826860

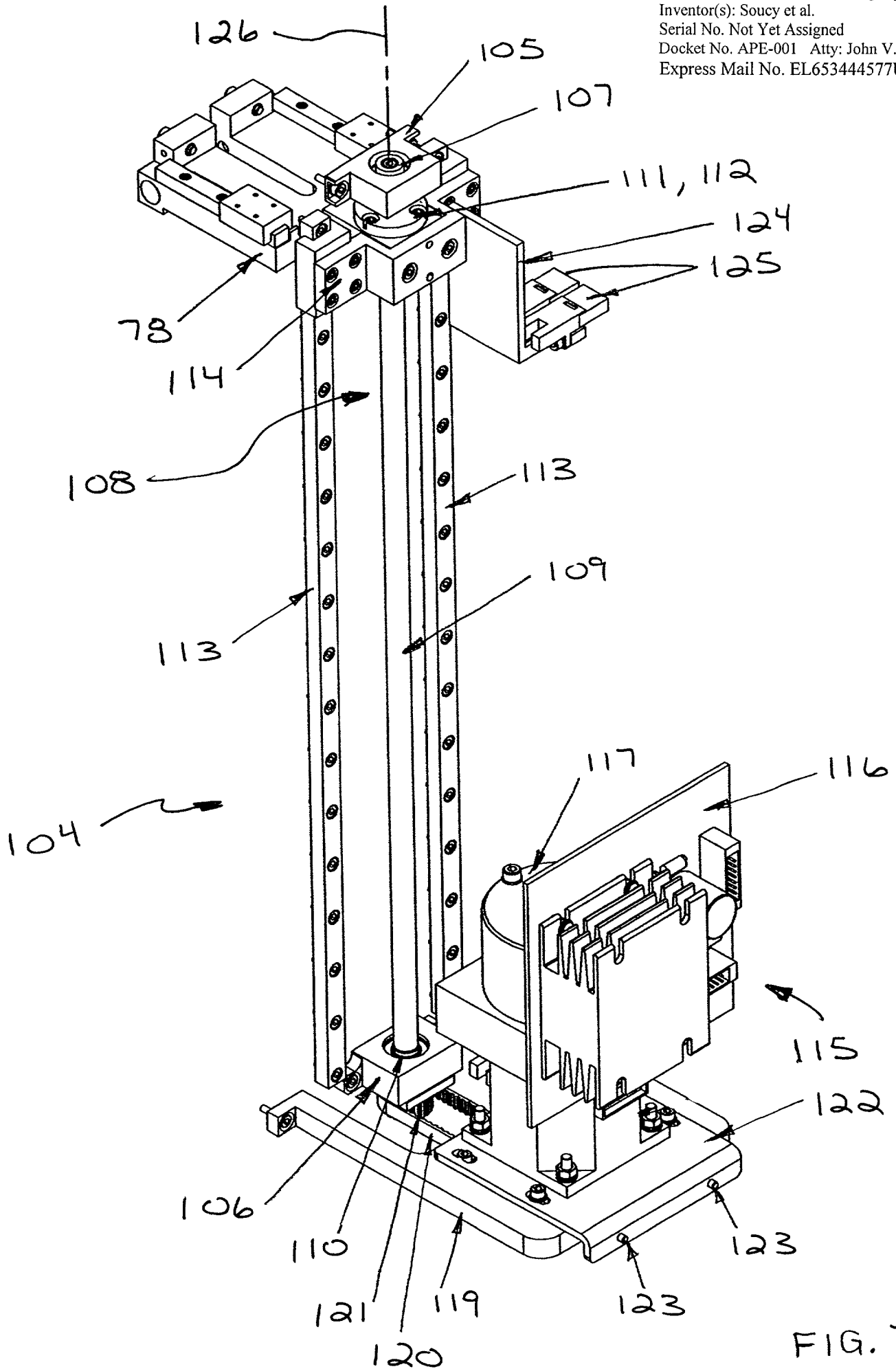


FIG. 7

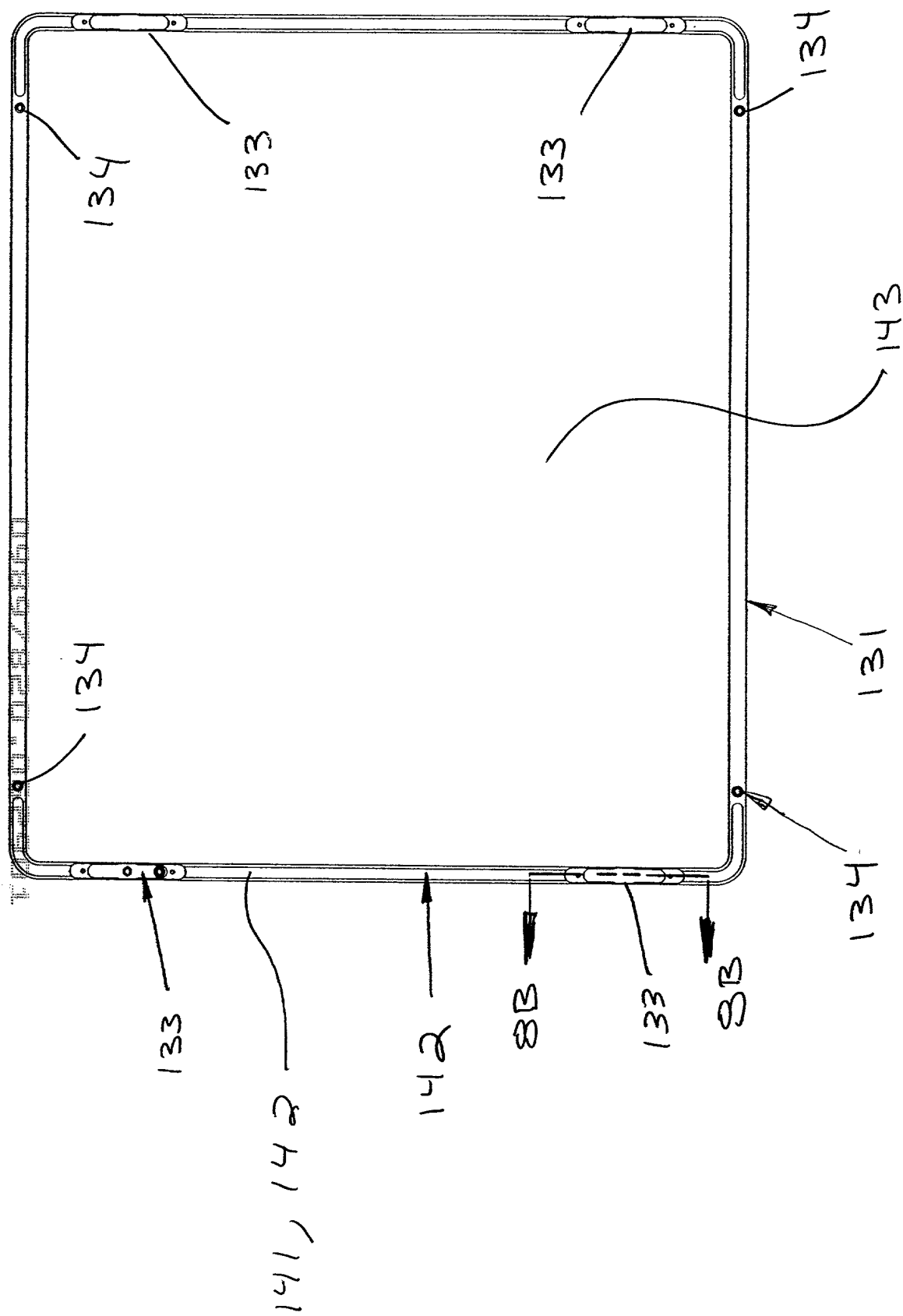


FIG. 2A

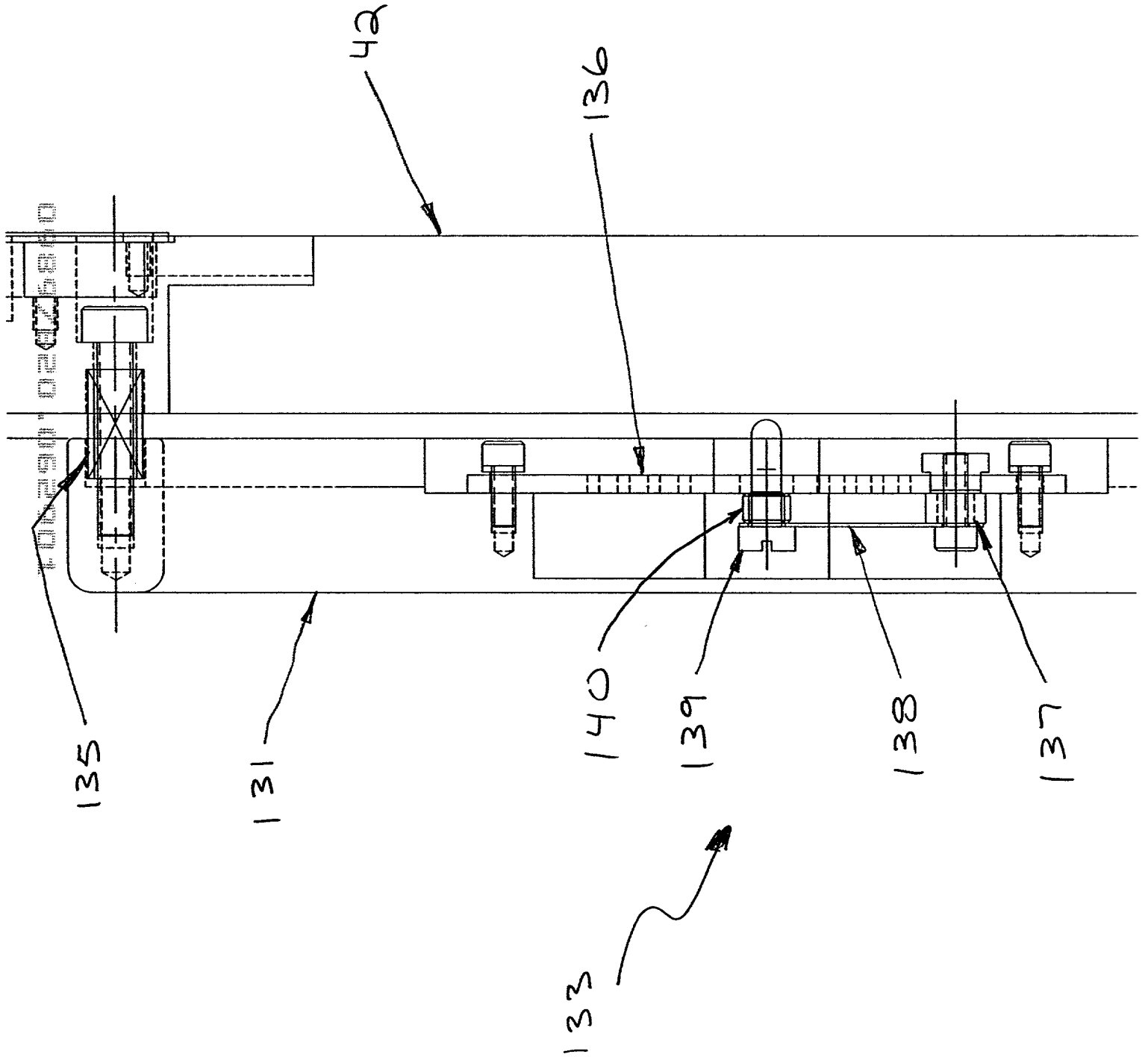


FIG. 8B



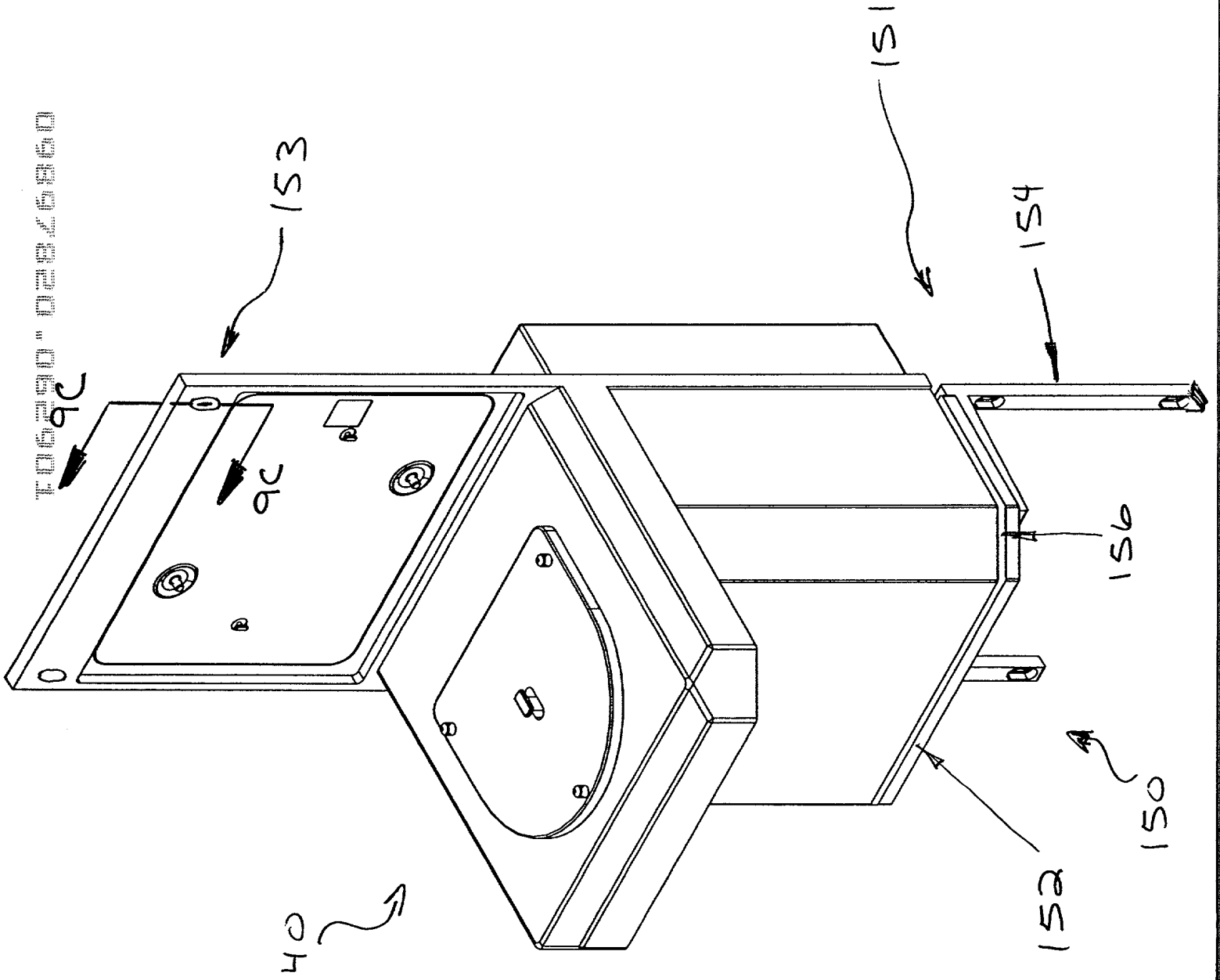


FIG. 9A

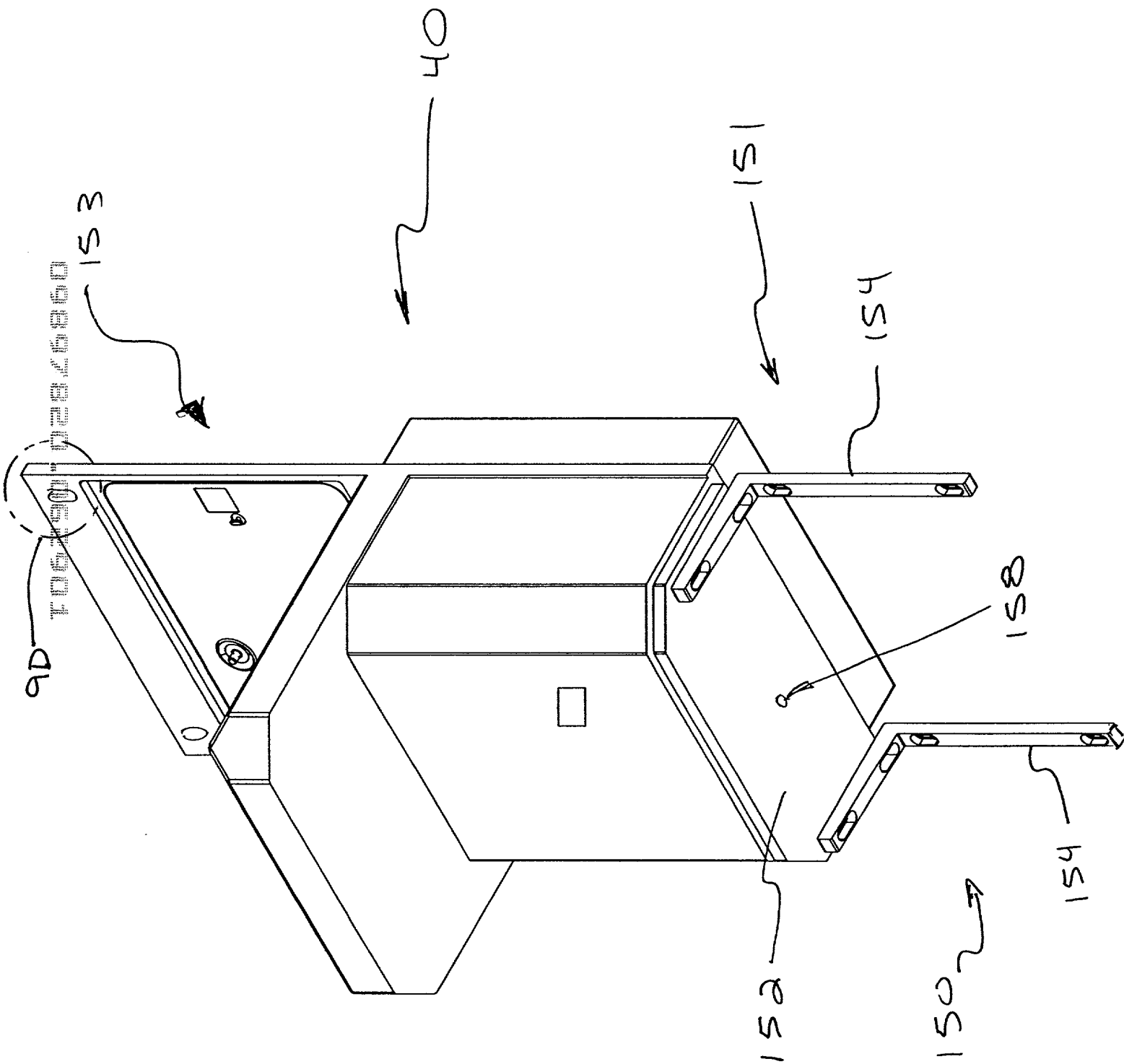


FIG. 9B

FIG. 9C

Title: Apparatus and Methods for  
Semiconductor Wafer Processing Equipment  
Inventor(s): Soucy et al.  
Serial No. Not Yet Assigned  
Docket No. APE-001 Atty: John V. Forcier  
Express Mail No. EL653444577US

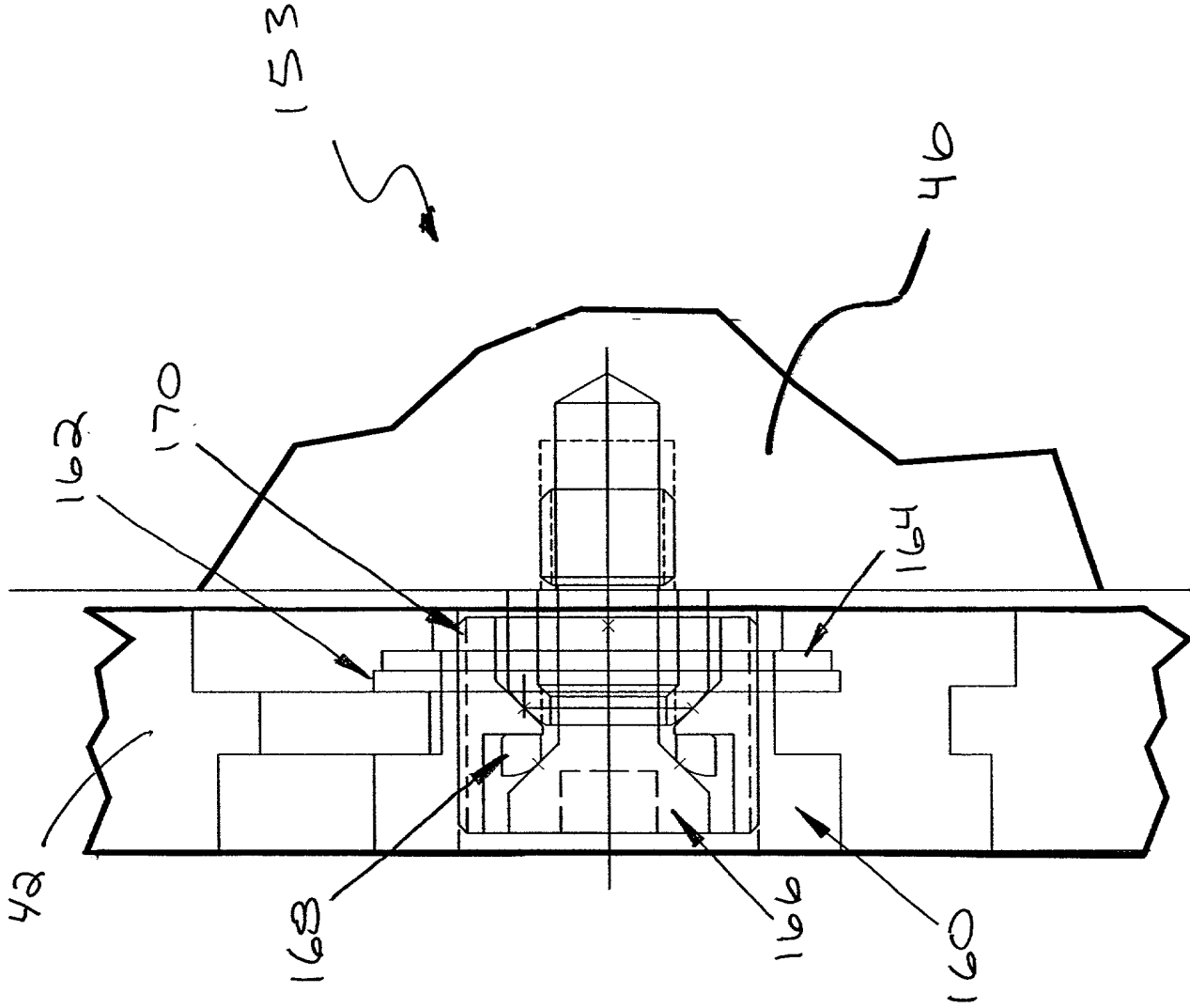


FIG. 9C

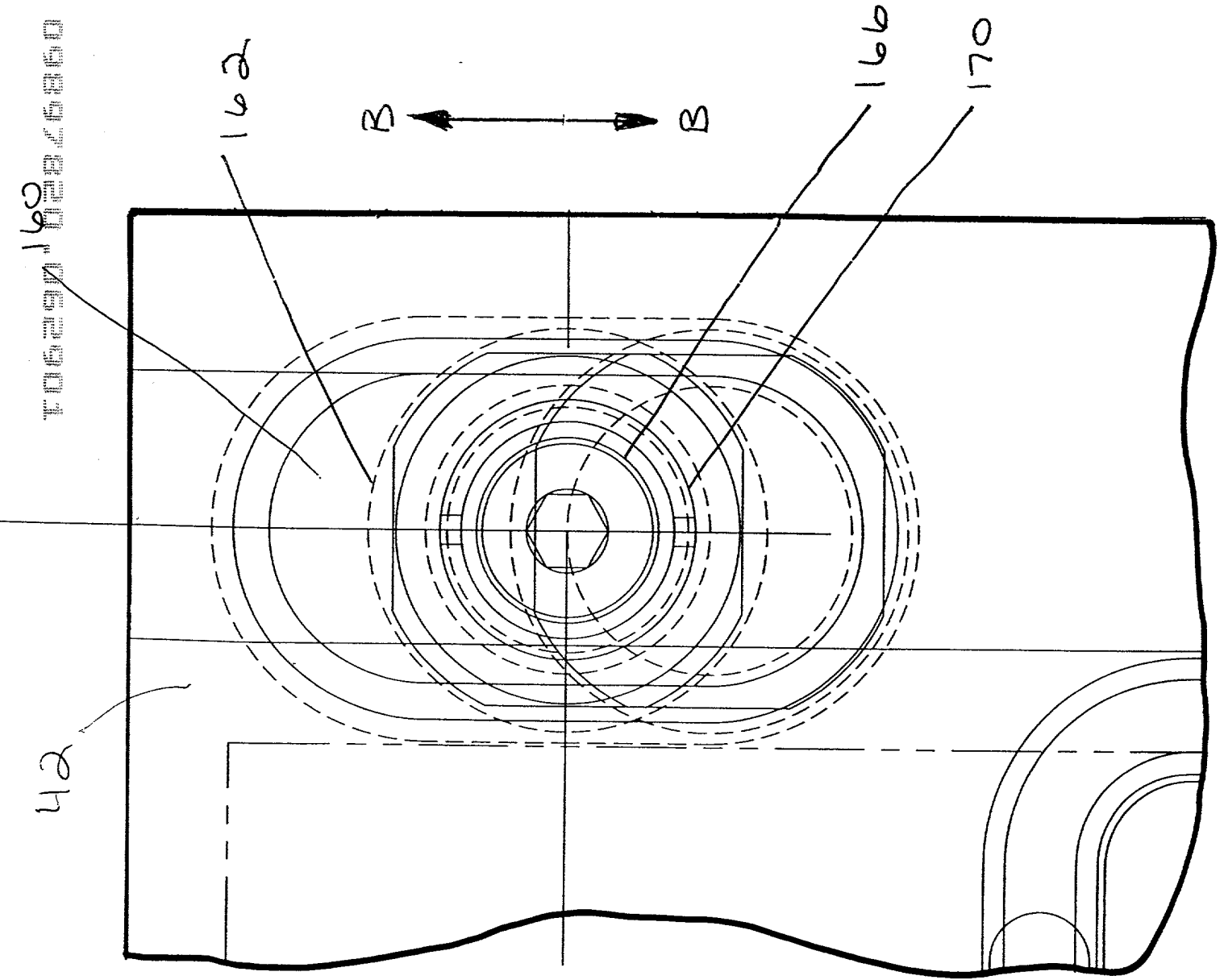


FIG. 9D

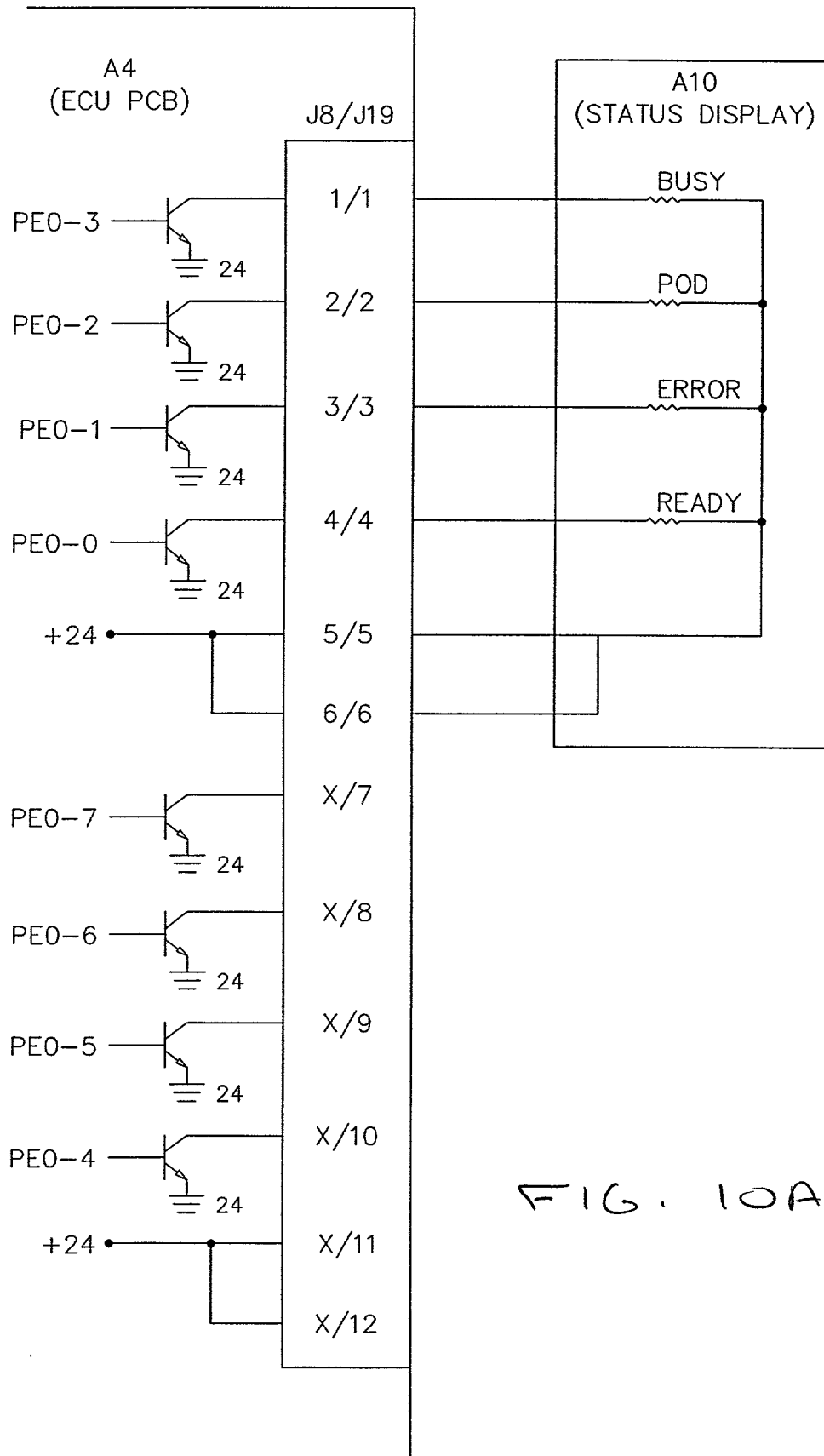


FIG. 10A

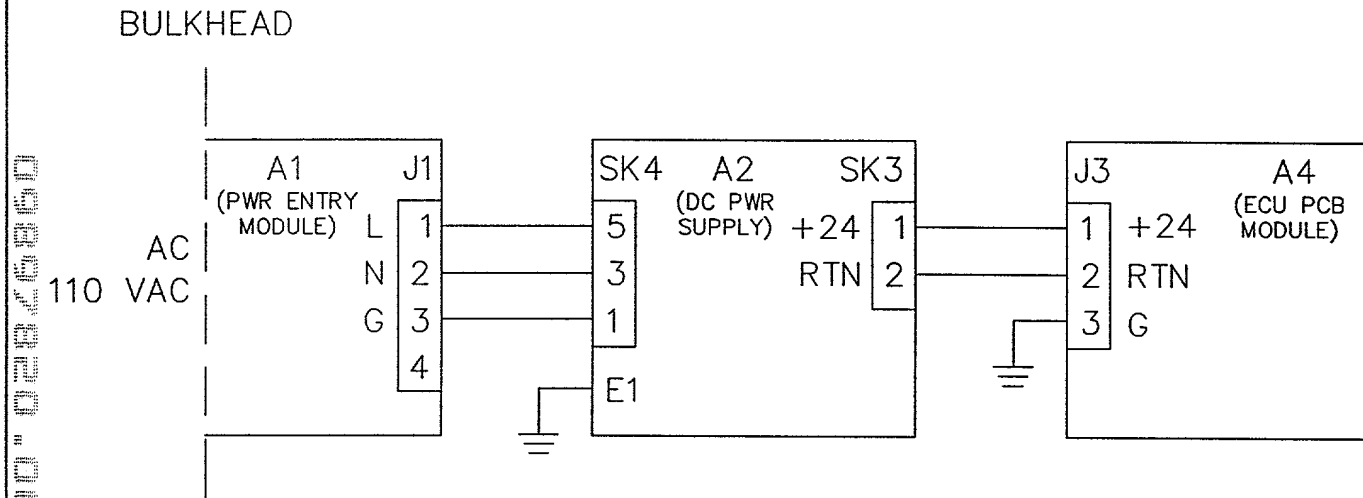


FIG. 10B

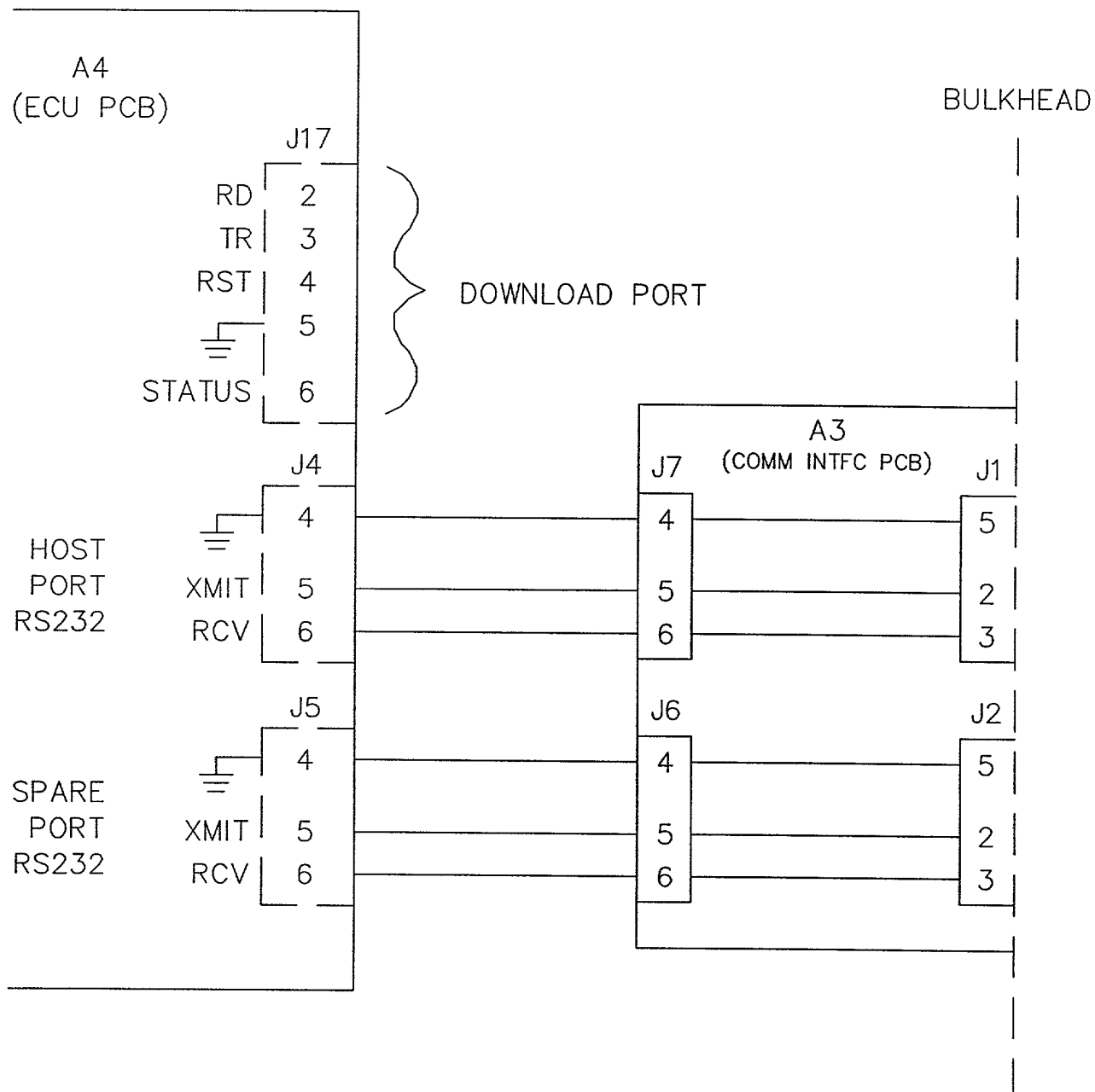


FIG. 10C

A5  
 (PNEUMATIC INTERFACE)

A4  
 (ECU PCB)

✕ = 24 VES

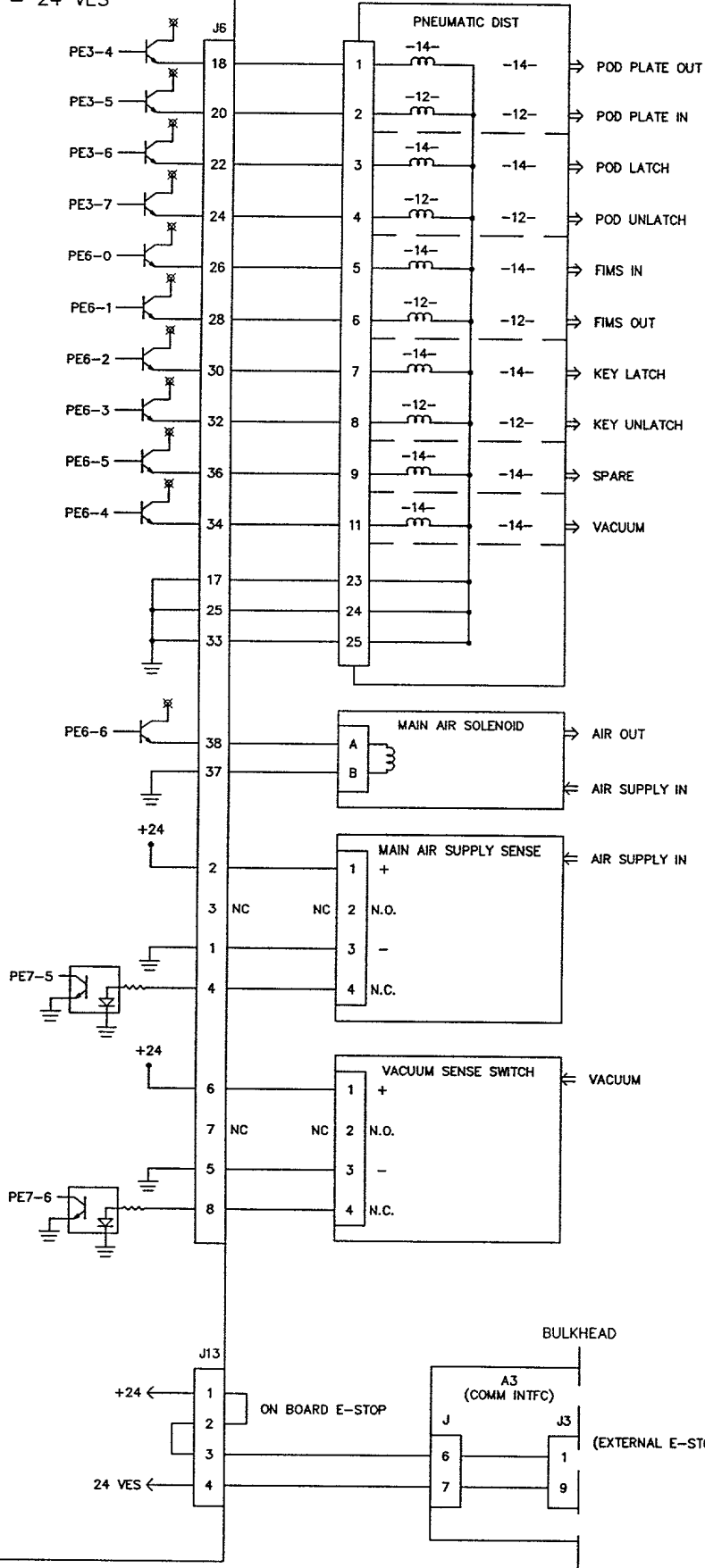


FIG. 10D



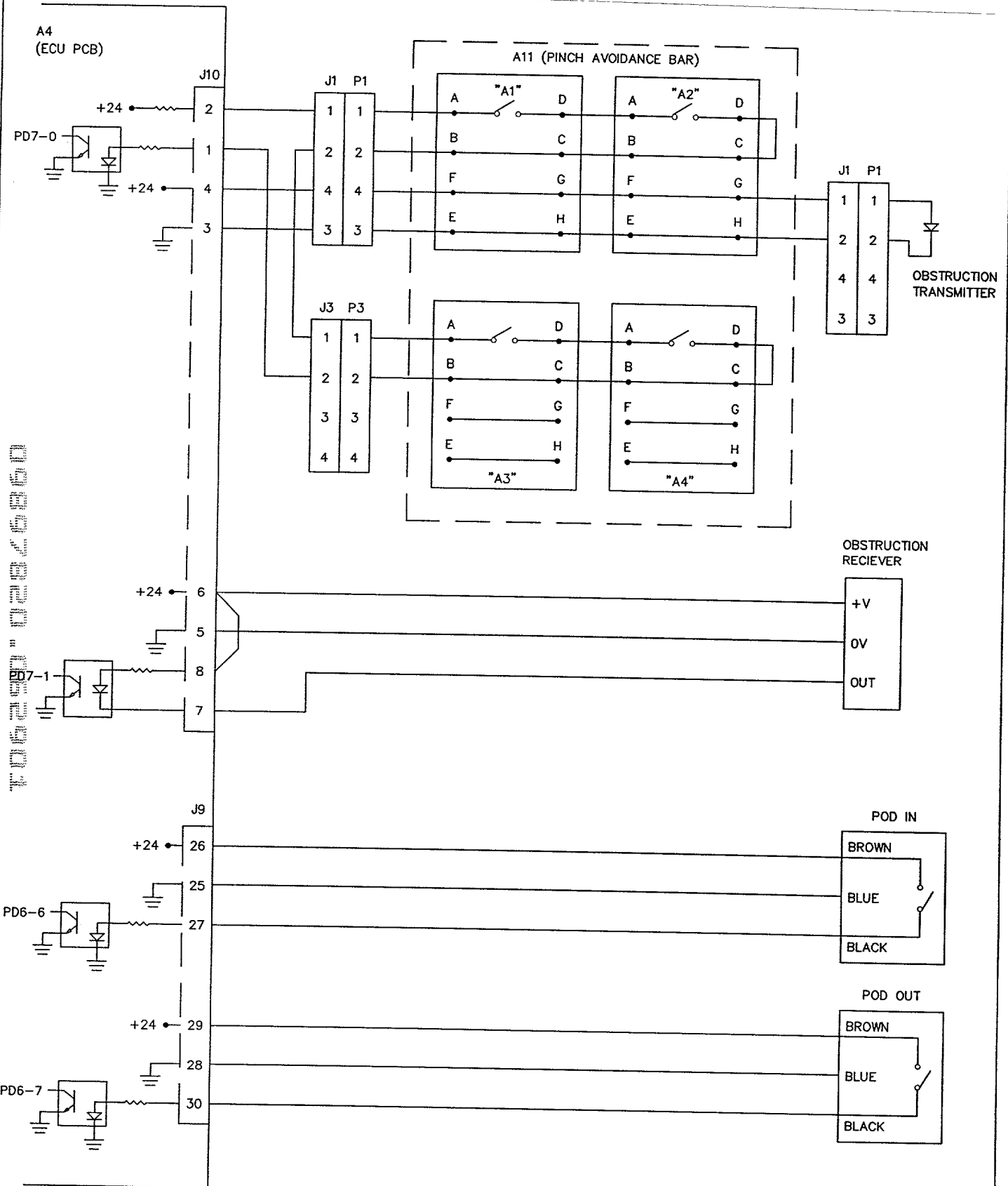


FIG. 10E



FIG. 106

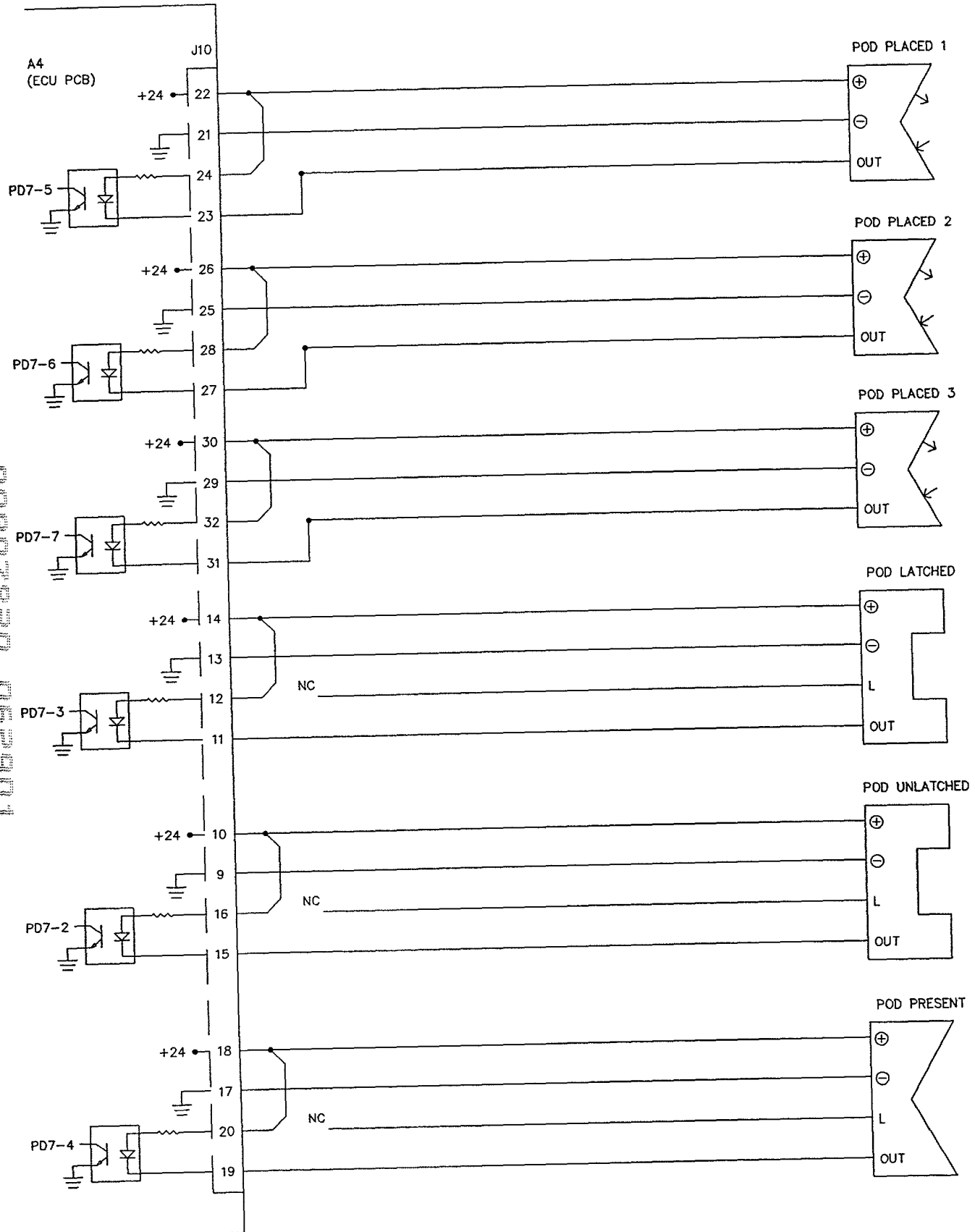


FIG. 106

